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(71) Applicant:

MATSUSHITA ELECTRIC IND CO

LTD

(72) Inventor:

MEGA HIRONAO KASAI KENJI

SATO HIROKAZU

(54) GALVANOMETER CONTROLLER

(57) Abstract:

PROBLEM TO BE SOLVED: To provide a galvanometer controller which is provided with a rotational position correcting means capable of fluctuated portion correcting thë characteristic of a position sensor quickly and highly accurately by a simple means in which the applying of fabrication is not necessary actually to a material to worked.

SOLUTION: In this galvanometer controller, when a correction mode is set when a fuctuation is generated in the output signal of a position sensor 9 by receiving the effect of environmental change or the like, a position instruction generating means 1 outputs a position instruction signal rotating a galvanometer 8 to a position where it is brought into contact with a mechanical limiter. When an instructed position by the position instruction signal at the point of time when the limit position of the galvanometer 8 is detected is different from a relational expression, the means 1 in which an arithmetic means 6 performs an operation changing the relational expression so as to correspond to the

fluctuated portion of the sensor instructed position instruction signal of thė position which is calculated based on the relational expression changed by the means 6.

